

Abstract Submitted
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**Positive Upper Critical Field Curvature in Niobium Thin Films:
Dependence on Purity** PHILLIP BROUSSARD, Covenant College, ANGELA
HUNZIKER, University of Basel — Thin films of niobium deposited by magnetron
sputtering have been characterized by critical field measurements with the magnetic
field applied perpendicular to the film plane. Film thickness varied from 16 to
100 nm, and using various deposition conditions, the parameter $\lambda_{tr} = 0.882\xi_0/\ell_{tr}$
(where ξ_0 is the BCS coherence length and ℓ_{tr} is the elastic mean free path) varied
from 2 to 14. Even films that are considered in the “dirty” limit ($\lambda_{tr} \gg 1$) show
positive curvature compared to the standard WHHM model. As λ_{tr} decreases, we
see a consistent rise in the curvature value, expressed by measuring $h/(1-t)$, where
 $h = B_{c2}(T)/B_{c2}(0)$ is the reduced field and $t = T/T_c$ is the reduced temperature.
We will compare to Nb films produced in other labs.

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